# OPAMP内蔵小型変位センサ

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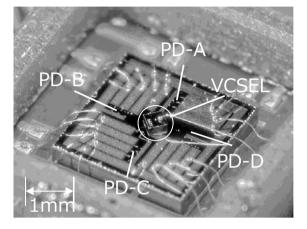






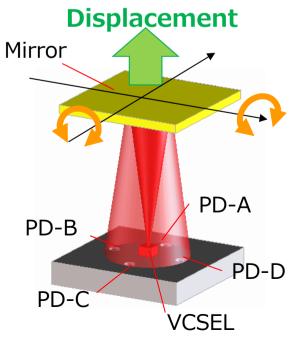
# **Micro Displacement Sensor**

Micro displacement Sensor



#### **Structure** : Small & Simple Sensor chip size:3000×3000×700(µm) VCSEL(laser diode):850nm, 2.5mW Photodiodes(PDs): 3 PDs in each direction

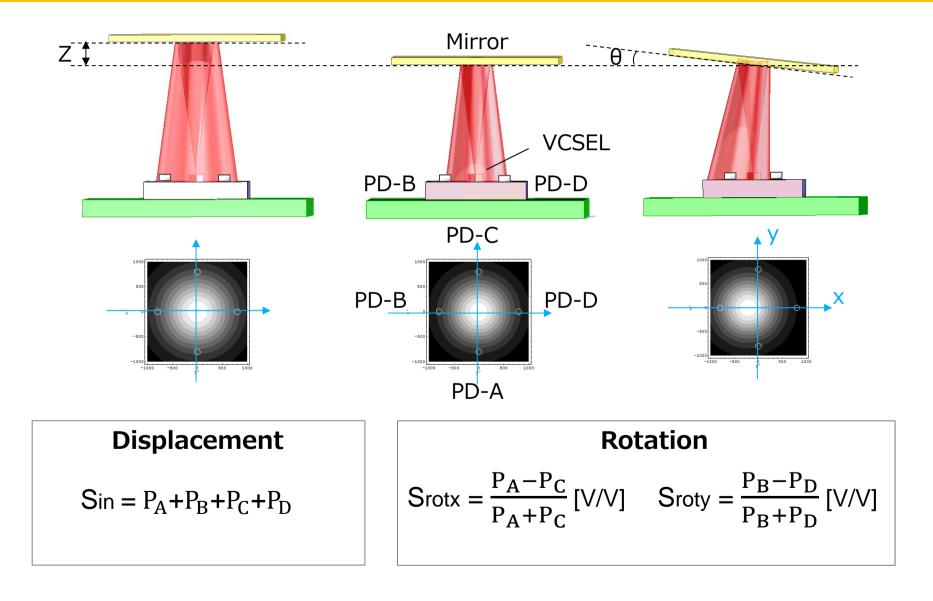
Measurement Displacement of the mirror Rotation of the mirror







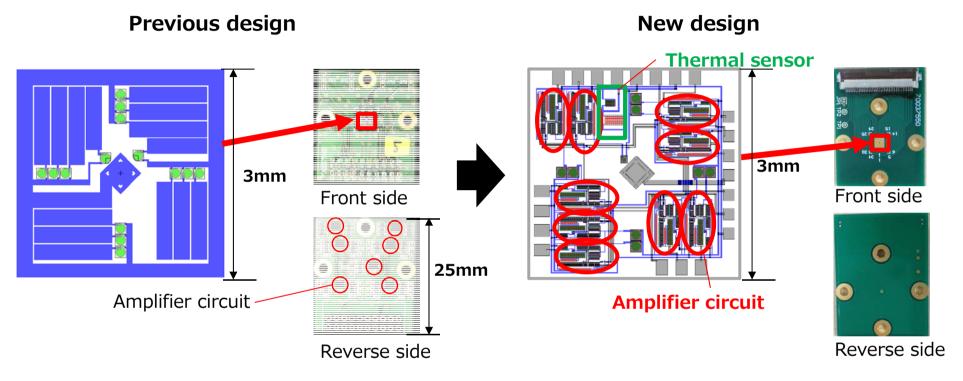
### **Principle**







# **Chip design**



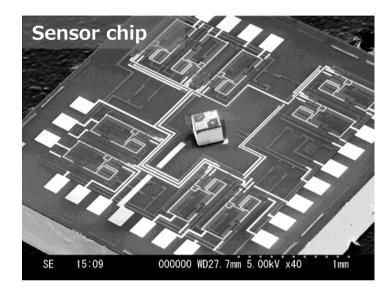
 $3 \times 4$  PDs + 2 Monitor PDs Amplifier circuit on the substrate  $\rightarrow$ whole sensor size become large

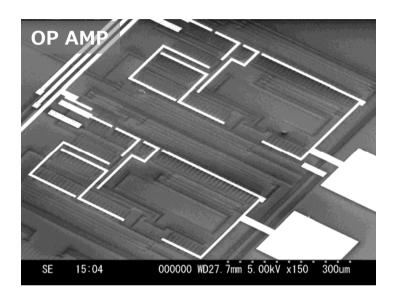
 $2 \times 4$  PDs + 1 Monitor PD Amplifier circuit in the chip  $\rightarrow$ whole sensor size can be smaller  $\rightarrow$ improve the noise

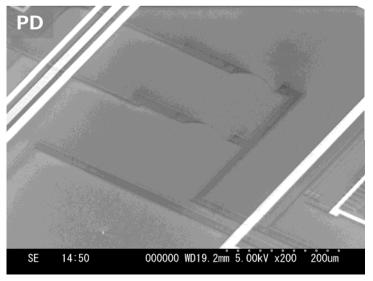


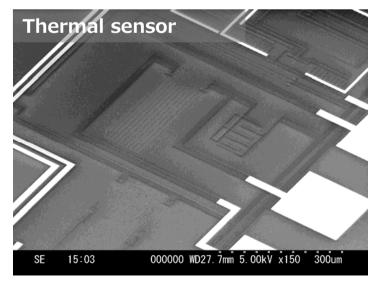


#### **Fabricated sensor chip**





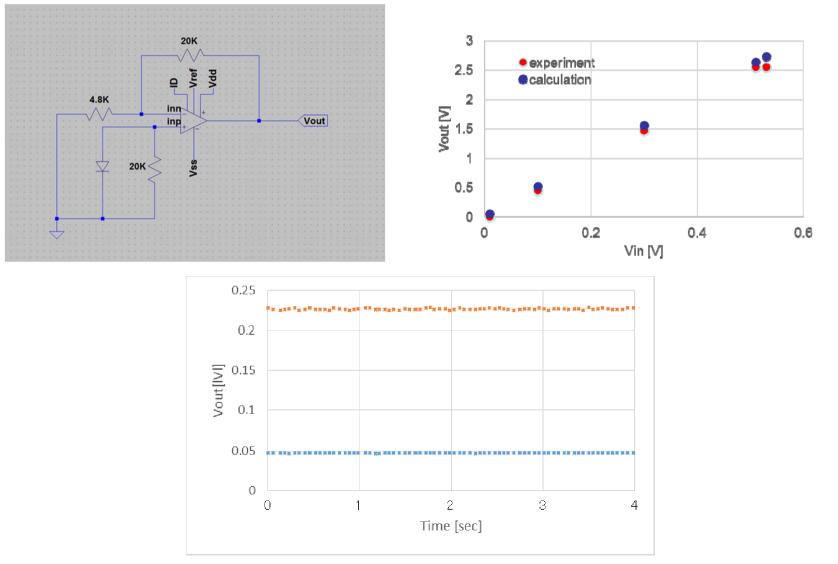








#### **Evaluation of Op amp**

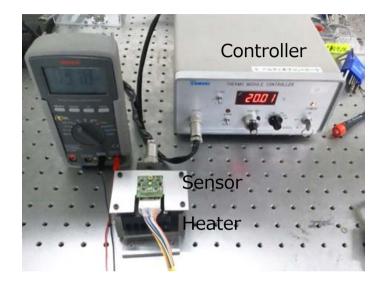


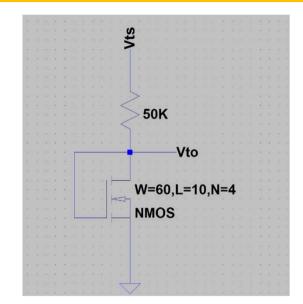
Output voltage of PD is amplified by OPAMP!

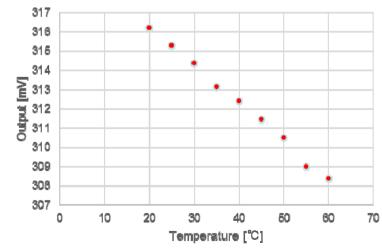




### **Evaluation of temperature sensor**





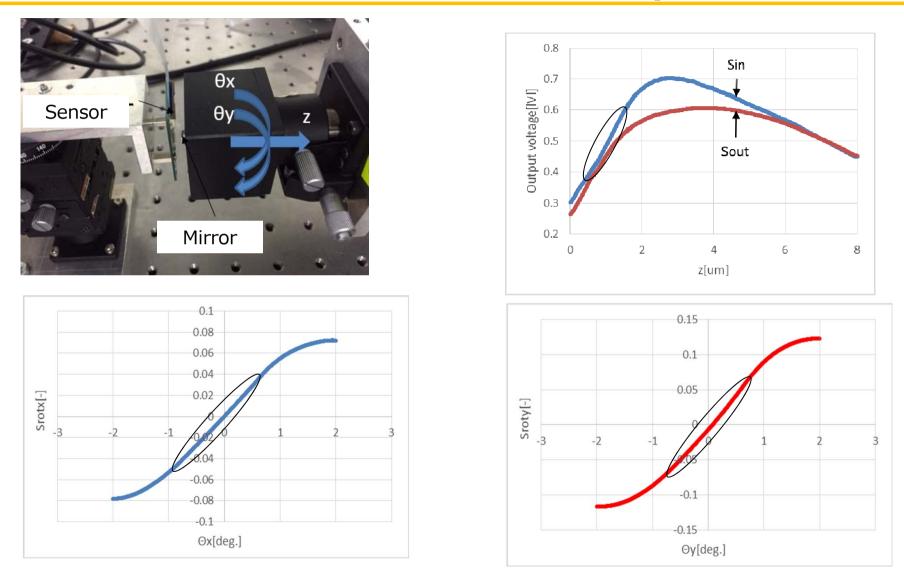


Thermal sensor can measure temperature of sensor chip !

KyushuUniversity The 5th Novel Device Design & Fabrication Contest in Hibikino



### **Evaluation of rotation and displacement**



Sensor can measure displacement and rotation angle around two axes !





# Conclusion

We fabricated displacement and rotation angle sensor. •Sensor chip size is 3000 [µm]×3000 [µm] and 700 [µm] in thickness. •OPAMP and Thermal sensor are integrated on this sensor chip.

Output voltage of PD is amplified using OPAMP. •Gain is about 4.9 [-] (non-inverting amplifier circuit)

Thermal sensor can measure tempreture of sensor chip. •The output changes linearly with measuring range of 20 [deg.] ~ 60 [deg.]

This Sensor can measure displacement and rotation angle around two axes.





#### Thank you for your kind attention.